# Development of the non-invasive beam size monitor using ODR

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## Introduction

For the ultra-low emittance and high intensity electron beam required by Linear Colliders and X-ray FEL,

conventional beam diagnostics (OTR monitor, solid wire scanner, etc.) are not applied to such beams because of the target destruction.

Therefore non-invasive beam diagnostics is necessary techniques for such accelerators.

Because of non-invasive nature, Diffraction radiation(DR) is one of candidates for application to non-invasive beam diagnostic.

However a very little experimental investigations exited.

Those experiments are measurements of coherent diffraction radiation ( $\lambda\sim1$ mm), incoherent diffraction radiation with visible light region (Optical Diffraction Radiation :ODR) hadn't been observed.

Since 2000, we have performed ODR experiments using low emittance electron beam extracted from KEK-ATF damping ring.

At first stage experiments,

we confirmed basic characteristics of ODR from the single edge target.

(T. Muto et al., Phys. Rev. Lett 90,104801(2003))

Now we have developed the beam size monitor using ODR.



## Principle of the ODR monitor

Coptical Diffraction Radiation-

The ODR appears when the charged particle passes near media with different dielectric constant.

ODR is emitted to two direction

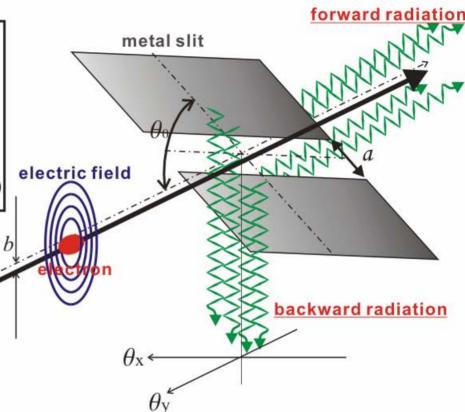
- along the particle (forward radiation)
- direction of reflection (backward radiation)

Beam size measurement using ODR

use the interference of ODRs from two halves of the slit target

#### Features of ODR monitor

- · non-invasive
- one-shot measurements
- · large observation angle
- good time resolution





# Principle (Cont.)

Angular distribution of the vertical polarization component of ODR

$$\frac{dWy}{d\omega d\Omega} = \frac{\alpha \gamma^2}{2\pi^2} \frac{\exp\left(-\frac{2\pi a \sin\theta_0}{\gamma \lambda} \sqrt{1 + t_x^2}\right)}{1 + t_x^2 + t_y^2}$$

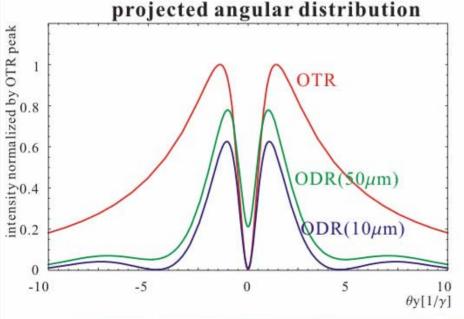
$$t_{x,y} = \gamma \theta_{x,y}$$
  $\psi = \arccos \frac{1 + t_x^2 - t_y^2}{1 + t_x^2 + t_y^2}$ 

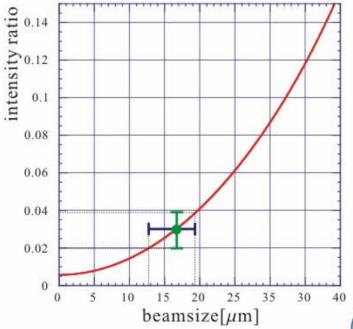
$$\left\{ \exp\left(\frac{8\pi^2}{\gamma^2\lambda^2} \sigma_y^2 (1+t_x^2)\right) c \right\}$$

$$\left\{ \exp\left(\frac{8\pi^2}{\gamma^2 \lambda^2} \frac{\sigma_y^2}{(1+t_x^2)}\right) \cosh\left(\frac{4\pi b}{\gamma \lambda} \sqrt{1+t_x^2}\right) - \cos\left(\frac{2\pi a \sin\theta_0}{\gamma \lambda} t_y + \psi\right) \right\}$$
(assume the beam has Gaussian distribution)

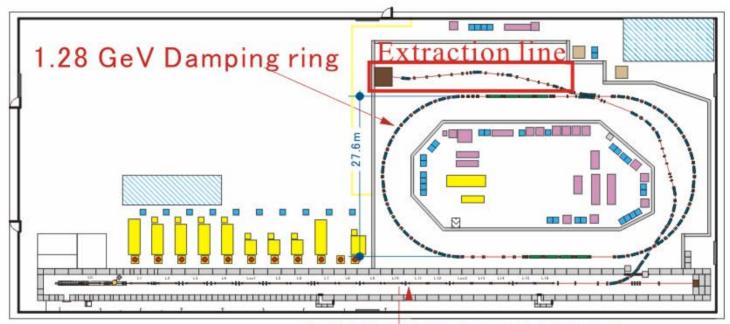
In order to increase the signal, we take integrate to the horizontal angle

beam size vs minimum-to-maximum intensity ratio





## KEK-ATF (Accelerator Test Facility)

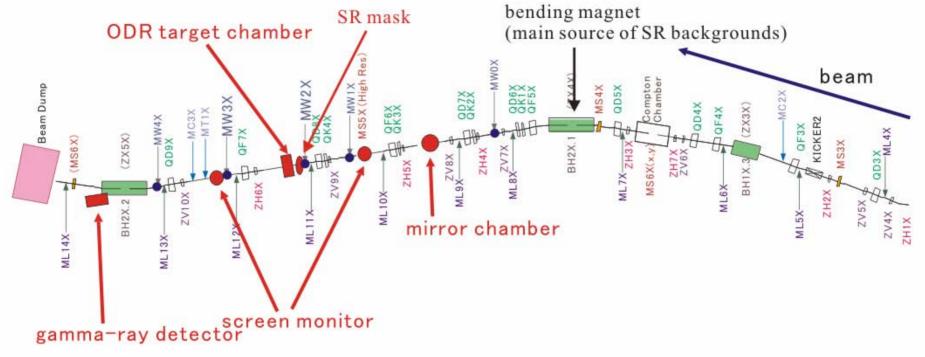


#### 1.28GeV S-band LINAC

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KEK-ATF parameter energy 1.28 GeV(\gamma~2500) emittance vertical ~5 pm rad horizontal ~1nm rad bunch length 20ps intensity 1.2 x 10^{10} electrons/bunch
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## Layout of the extraction line



The emittance can be measured by 5 wire scanners.

At the ODR measurements,

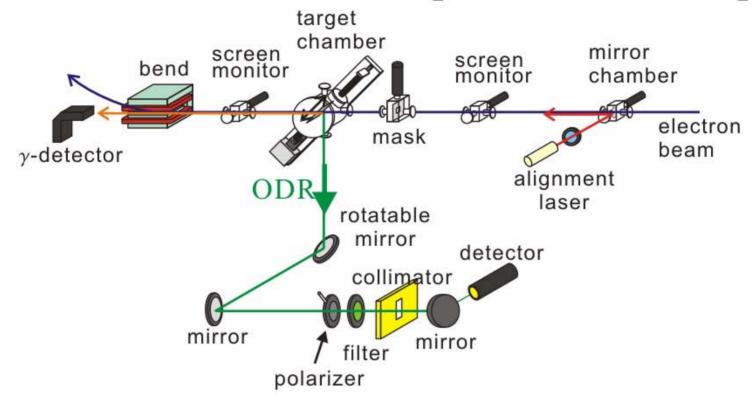
emittance measurements was done.

Using measured parameters,

the optics for ODR measurements was calculated by SAD.



## Schematic view of the experimental set up



collimator size:  $v = 0.2(=0.142\gamma^{-1})x + 24(=15.2\gamma^{-1})mm$ 

rotatable mirror accuracy: vertical=19 $\mu$ rad, horizontal=35 $\mu$ rad

target position read accuracy:  $0.5\mu m$  filter wavelength region:  $550\pm20 nm$ 

light detector: PMT(Hamamatsu H1161)

γ-detector : Air Cherenkov counter

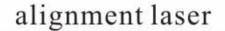
alignment accuracy :  $<100\mu m(position)$ ,  $<42\mu rad (angle)$ 



# the ODR chamber and the alignment laser



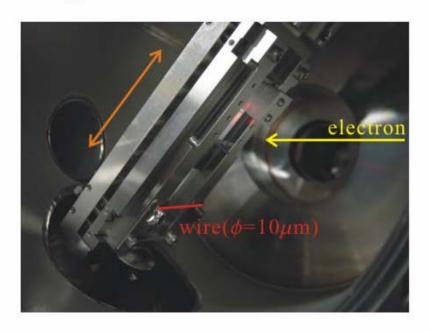
target chamber





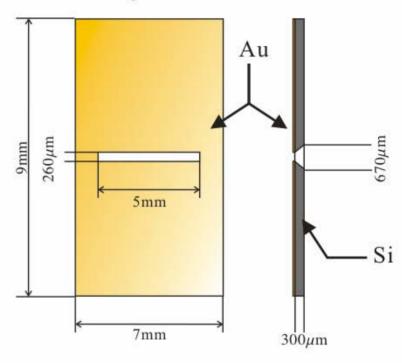


#### Target and wire



target property	
silicon thickness	$300 \mu \mathrm{m}$
gold foil thickness	$\sim 1 \mu \mathrm{m}$
edge uniformity	1−2 <i>μ</i> m
average roughness	20nm
Maximum roughness	150nm

#### slit target



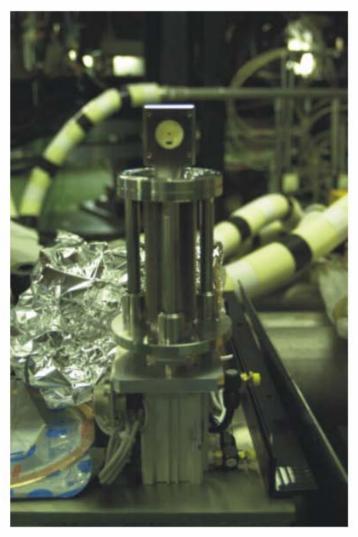
Silicon wafer covered with gold

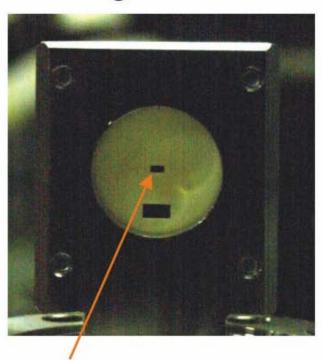


#### 8 July 2004, EPAC04, Lucerne

#### SR mask

To avoid the contribution of synchrotron radiation(SR), we installed "SR mask" in front of the target chamber.





1x2mm hole on the ceramic plate

poster: THPLT067

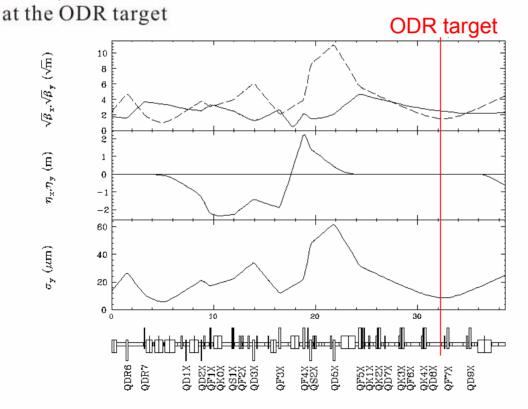


# Optics and Wire-scanning

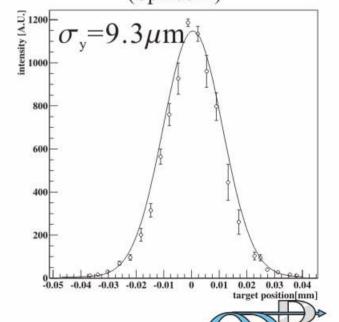
In order to avoid SR background, the optics is all most quad and steer magnets after last bending magnet is turn off.

three different optics calculated by SAD were prepared

- $\sigma_y = 9 \mu m \text{ (optics A)}$
- $\sigma_y = 15 \mu m$  (optics B)
- $\sigma_y = 25 \mu m$  (optics C)

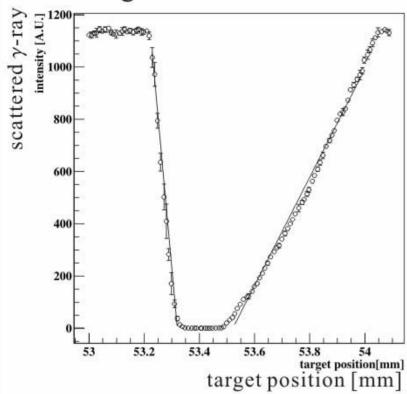


beam size measured by wire scanner (optics A)



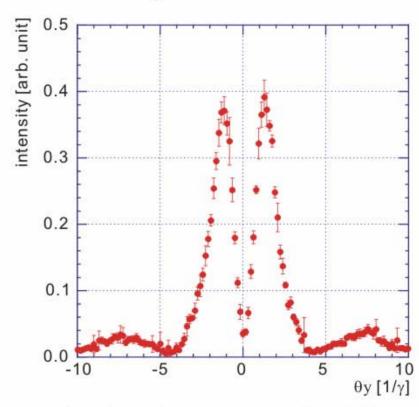
## Results

#### Target scan



by this scan, slit center was obtained

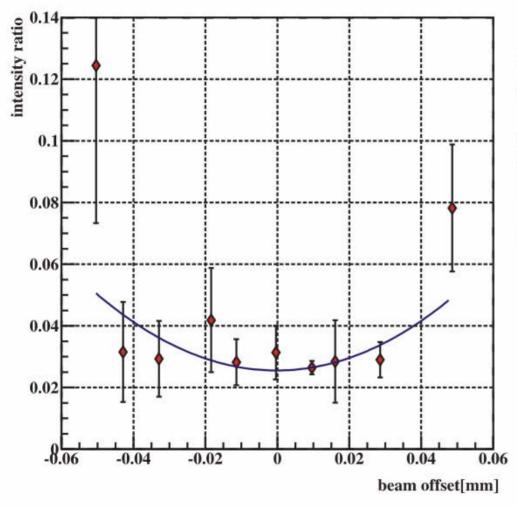
#### ODR angular distribution



clear interference pattern by ODR was observed.



### Minimum-to-maximum ratio vs the target position (optics B)



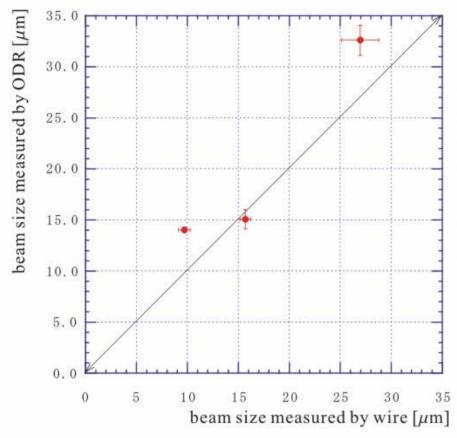
The solid line represents the parabolic fit.

From parabolic fit minimum-to-maxmum intensity ratio was obtained.

Only statics error is shown.



#### The comparison with measurements by the wire-scanning



Beam sizes measured by the ODR monitor has a sensitivity around  $20\mu m$  electron beam size.

Beam sizes measured by the ODR monitor were larger than measured by wire scanner.

It indicate that there are some systematic errors.

During this measurements, the beam extraction was not stable, because of the extraction kicker's timing jitter.



## Summary

- We performed the beam size measurements using ODR.
- The ODR interference pattern from the slit target was observed, and that has a sensitivity to electron beam size.
- From the comparison with beam sizes measured by the wire scanner, theare are some systematic errors.
- During this measurements, the beam orbit was unstable because of kicker. We should need to more intensive study. And in order to increase sensitivity, we will measured ODR with shorter wavelength.

